

Attorney's Docket No. P00743/70003

# K:

#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Stephen D. SENTURIA

8-22-02

Serial No.:

سن 381,090,181

Filing Date:

March 4, 2002

For:

METHODS AND APPARATUS FOR WAVELENGTH-BASED OPTICAL

**PROCESSING** 

Examiner:

Unassigned

Art Unit:

Confirmation No.

Commissioner for Patents Washington, D.C. 20231

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AUG 2 1 2002

Sir/Madam:

**Technology Center 2600** 

Transmitted herewith for filing is/are the following document(s):

[X] Supplemental Information Disclosure Statement

[X] PTO Form 1449 With Cited References

[X] Return Post Card

If the enclosed papers are considered incomplete, the Mail Room and/or the Application Branch is respectfully requested to contact the undersigned collect at (617)720-3500, Boston, Massachusetts.

No check is enclosed. If it is determined that a fee is necessary, the fee may be charged to the account of the undersigned, Deposit Account No. 23/2825. A duplicate of this sheet is enclosed.

#### CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

I hereby certify that this document is being placed in the United States mail with first-class postage attached, addressed to the Commissioner for Patents, Washington, D.C. 20231 on August 5, 2002.

Respectfully submitted,

Stephen D. SENTURIA

Jeffrey B. Powers

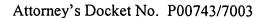
Registration No. 45,021

WOLF, GREENFIELD & SACKS, P.C.

600 Atlantic Avenue Boston, MA 02210 Tel. (617)720-3500

Attorneys for the Applicant(s)

Attorney's Docket No. P00743/7003





#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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# SUPPLEMENTAL STATEMENT FILED PURSUANT TO THE DUTY OF DISCLOSURE UNDER 37 CFR §1.56, 1.97 AND 1.98

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. §§1.56, 1.97 and 1.98, the Applicant requests consideration of this Information Disclosure Statement.

### Compliance with 37 C.F.R. §1.97

This Information Disclosure Statement is being filed before the mailing date of a first Office Action on the merits in the above-identified case. No fee or certification is required.

#### Information Cited

The Applicant hereby makes of record in the above-identified application the information listed on the attached form PTO-1449 (modified). The order of presentation of the references should not be construed as an indication of the importance of the references.

#### REMARKS

Documents cited on the attached form PTO-1449 (modified) are enclosed unless otherwise indicated on the attached form PTO-1449 (modified). It is respectfully requested that:

1. The Examiner consider completely the cited information, along with any other information, in reaching a determination concerning the patentability of the present claims;

Art Unit:

- 2. The enclosed form PTO-1449 be signed by the Examiner to evidence that the cited information has been fully considered by the Patent and Trademark Office during the examination of this application;
- 3. The citations for the information be printed on any patent which issues from this application.

By submitting this Information Disclosure Statement, the Applicant makes no representation that a search has been performed, of the extent of any search performed, or that more relevant information does not exist.

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, material to patentability as defined in 37 C.F.R. §1.56(b).

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, in fact, prior art as defined by 35 U.S.C. §102.

Notwithstanding any statements by the Applicant, the Examiner is urged to form his own conclusion regarding the relevance of the cited information.

An early and favorable action is hereby requested.

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

I hereby certify that this document is being placed in the United States mail with first-class postage attached, addressed to the Commissioner for Patents, Washington, D.C. 20231 on August /\_\_\_\_, 2002.

Attorney's Docket No. P00743/70003

Respectfully submitted,

Stephen D. SENTURIA

Jeffrey B. Powers

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Attorneys for the Applicant(s)

AUG 1 9 20072		
FORM PTO-1449/45 and B (Modified)	APPLICATION NO.: 10/090,381 ATTY. DOCKET NO.: P00743/70003	
INFORMATION DISCLOSURE	FILING DATE: March 4, 2002	
STATEMENT BY APPLICANT	APPLICANT: Stephen D. SENTURIA	
Sheet 1 of 9	GROUP ART UNIT: EXAMINER:	

Examiner's	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue
Initials #	No.	Number Kind Code		Document	of Cited Document MM-DD-YY
		3,553,364		Lee	01/05/71
		4,234,788		Palmer et al.	11/18/80
		4,731,670		Allen et al.	03-15-1988
		4,805,038		Seligson	02-14-1989
		5,022,745		Zayhowski et al.	06/11/91
		5,115,344		Jaskie	05-19-1992
		5,164,688		Larson RECEIV	ED 11/17/92
		5,168,249		Larson RECEIV	12/01/92
		5,175,521		Larson AUG 2 1 2	<b>12/29/92</b>
		5,206,557		Bobbio	04/27/93
		5,212,582		Nelson Technology Cen	er 2600 <sub>05/18/93</sub>
		5,291,502		Pezeshki et al.	03/01/94
		5,311,360		Bloom et al.	05-10-1994
		5,353,641		Tang	10/11/94

#### FOREIGN PATENT DOCUMENTS

F	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited	Date of Publication of	Translation
Examiner's Initials #		Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)
		WO	98/41893	A1		09-24-1998	
		wo	91/02991	A1		03-07-1991	

#### OTHER ART -- NON PATENT LITERATURE DOCUMENTS

Examiner's	Cite	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the	Translation
Initials #	No	item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue	(Y/N)
		number(s), publisher, city and/or country where published.	
		MICROMECHANICAL LIGHT MODULATOR ARRAY FABRICATED ON SILICON, K.E. PETERSEN, IBM	
		Research Lab., Applied Physics Letters, Vol. 31, No. 8, 10/15/77, pp 521-523	

EXAMINER	DATE CONSIDERED

#EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

\*a copy of this reference is not provided as it was previously cited by or submitted to the office in a prior application, Serial No. \_\_\_\_\_\_\_, filed \_\_\_\_\_\_, and relied upon for an earlier filing date under 35 U.S.C. 120 (continuation, continuation-in-part, and divisional applications).

AUG 1	2007						
FORM PTO-14: A and B (Modified)					APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003
	FORMATION	-	_		FILING DATE: March 4, 2002		
STATEMENT BY APPLICANT				ANT	APPLICANT: Stephen D. SENTURIA		
Sheet	2	of	<u> </u>	9	GROUP ART UNIT:		EXAMINER:

Examiner's Initials #	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue
	No.	Number	Kind Code	Document	of Cited Document MM-DD-YY
		5,392,151		Nelson	02/21/95
		5,396,066		Ikeda et al.	03/07/95
		5,459,610		Bloom et al.	10-17-1995
-		5,561,523		Blomberg et al.	10/01/96
		5,629,951		Chang-Hasnain et al.	05/13/97
		5,640,133		MacDonald et al.	06/17/97
		5,646,772		Yurke HEC	EIVED7/08/97
		5,654,819		0 1	
		5,661,592		Bornstein et al.	<b>2 1 2002</b> 8-26-1997
		5,677,783		Bloom et al. <b>Technolog</b>	v Center 25 m 1997
		5,696,662		Bauhahn	12/09/97
		5,739,945		Tayebati	01/14/98
****		5,745,271		Ford et al.	04-28-1998

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	Cite No.	Foreign Patent Document		ment	Name of Patentee or Applicant of Cited	Date of Publication of	Translation
Examiner's Initials #		Office/ Country	Number	Kind Code	(not necessary) Docum	Cited Document MM-DD-YY	(Y/N)
		WO	01/11394	A1		02-15-2001	
		wo	01/11419	A2	Godil et al.	15-02-2001	
		WO	01/11410	<b>A</b> 1	Thackara et al.	02/15/01	
		WO	01/11396	A1		02-15-2001	

#### OTHER ART - NON PATENT LITERATURE DOCUMENTS

Examiner's	Cite	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the	Translation
Initials #	No	item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue	(Y/N)
		number(s), publisher, city and/or country where published.	
		MINIATURE FABRY-PEROT INTERFEROMETERS MICROMACHINED IN SILICON FOR USE IN OPTICAL FIBER WDM	
	1	SYSTEMS, J.H. JERMAN et al., IEEE 1991 372, International Conf. On Solid-State Sensors and	
		Actuators 1991, pp 372-375	

EXAMINER	DATE CONSIDERED

#EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

AUG	9 2002						
FOR PTO	2-144946 and B (M	lodifie	d)	APPLICATION NO.: 10/090,3	81 ATTY. DOCKET NO.: P00743/70003		
	FORMATION			FILING DATE: March 4,	FILING DATE: March 4, 2002		
ST	ATEMENT B	Y Al	PPLICANT	APPLICANT: Stephen	APPLICANT: Stephen D. SENTURIA		
Sheet	3	of	9	GROUP ART UNIT:	EXAMINER:		

Examiner's	Cite	U.S. Patent Document		Name of Patentee or Applicant of Cited	Date of Publication or of issue of Cited Document
Initials #	No.	Number	Kind Document Code	Document	MM-DD-YY
		5,757,536		Ricco et al.	05-26-1998
		5,781,670		Deacon et al.	07-14-1998
		5,794,023		Hobbs et al.	08-11-1998
		5,808,797		Bloom et al.	EIVED 08-11-1998
		5,836,203		Martin et al. ALC 9	1 2002 11-17-1998
	1	5,841,579		Bloom et al.	11-24-1998

# **Technology** Center 2600

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Examiner's Initials #	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited	Date of Publication of	Translation
		Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)
		wo	01/42825	A1	Gutin	06/14/01	
		EP	1 122 577	A2		08-08-2001	
		EP	1 143 287	A2		10-10-2001	

#### OTHER ART -- NON PATENT LITERATURE DOCUMENTS

Examiner's	Cite	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the				
Initials # No		item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.				
		Solgaard et al., "Deformable grating optical modulator," Optics Letters, Vol. 17, No. 9, May 1, 1992, pgs. 688-690.				
		Goossen et al., "Silicon Modulator Based on Mechanically-Active Anti-Reflection Layer with 1 Mbit/sec Capability for Fiber-in-the-Loop Applications," <u>IEEE Photonics Technology Letters</u> , Vol. 6, No. 9, September 1994, pgs. 1119-1121.				
		SPECTRALLY SELECTIVE GAS CELL FOR ELECTROOPTICAL INFRARED COMPACT MULTIGAS SENSOR, MELÉNDEZ et al., Elsevier Science S.A., Sensors and Actuators 46-47 (1995) 417-421				
		SILICON MICROMACHINED INFRARED SENSOR WIHT TUNABLE WAVELENGTH SELECTIVITY FOR APPLICATION IN INFRARED SPECTROSCOPY, D. ROSSBERG., Elsevier Science S.A., Sensors and Actuators 46-47 (1995) 413-416				
		CONTINUOUS-MEMBRANE SURFACE-MICROMACHINED SILICON DEFORMABLE MIRROR, BIFANO et al., Soc. of Photo-Optical Ins. Eng. Opt. Eng. 36(5) May 1997, pp 1354-1360				

EXAMINER	DATE CONSIDERED

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AUG 1 9	NOUS F		•			
FERMATIO	A and B (M	lodified	)	APPLICATION NO.: 10	0/090,381	ATTY. DOCKET NO.: P00743/70003
	FORMATION		FILING DATE: M	FILING DATE: March 4, 2002		
STATEMENT BY APPLICANT				APPLICANT: S	tephen D.	SENTURIA
Sheet	4	of	9	GROUP ART UNIT:		EXAMINER:

Examiner's Initials #	Cite	U.S. Patent Document		Name of Patentee or Applicant of Cited	Date of Publication or of issue	
	No.	Number	Kind Code	Document	of Cited Document MM-DD-YY 12-08-1998	
		5,847,859		Murata		
	5,870,221			Goossen	02-09-1999	
		5,905,571		Butler et al.	05/18/99	
		5,905,589		Tanaka et al. RECEI	/FD 05-18-1999	
		5,920,418		Shiono et al.	07-06-1999	
		5,933,277		Troxell et al. AUG 2 1	2002 08/03/99	
		5,949,568		Koo et al	09/07/99	
		5,949,570		Shiono et al. lechnology Ce	nter 2600 <sub>9-07-1999</sub>	
		5,953,161		Troxell et al.	09-14-1999	

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Examiner's Initials #	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited	Date of Publication of	Translatio	on
		Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)	

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Initials #	No	item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue					
		number(s), publisher, city and/or country where published.					
		MOCRO-ACTUATED MIRRORS FOR BEAM STEERING, GUSTAFSON et al., SPIE- Society of Photo-Optical Instrumentation Engineering, Vol. 3008, 1997, pp 90-99					
		DESIGNS TO IMPROVE POLYSILICON MICROMIRROR SURFACE TOPOLOGY, BURNS et al., SPIE- Society of Photo-Optical Instrumentation Engineering, Vol. 3008, 1997, pp 100-110					
		OPTICAL BEAM STEERING USING SURFACE MICROMACHINED GRATINGS AND OPTICAL PHASED ARRAYS, BURNS et al., SPIE, Vol. 3131, 1997, pp 99-110					
		INVESTIGATION OF THE MAXIMUM OPTICAL POWER RATING FOR A MICRO-ELECTRO-MECHANICAL DEVICE, BURNS et al., Internat'l Conf. On Solid-State Sensors and Actuators 06/16/97-06/19/97, pp 335-338					

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AUG 1	9 2002				•		
FORMAT	and B (M	odifie	d)	APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003	
INI	FORMATION	DIS	CLOSURE	FILING DATE:	FILING DATE: March 4, 2002		
ST	ATEMENT B	Y A	PPLICANT	APPLICANT:	Stephen D.	SENTURIA	
Sheet	5	of	9	GROUP ART UNIT:		EXAMINER:	

Examiner's	Cite	U.S. Patent Document		Name of Patentee or Applicant of Cited	Date of Publication or of issue of Cited Document	
Initials #	No.	Number	Kind Code	Document	MM-DD-YY	
		5,966,235		Walker	10/12/99	
		5,969,848		Lee et al.	10/19/99	
		5,978,127		Berg	11/02/99	
-		5,991,079		Furlani et al.	11-23-1999	
		5,998,906		Jerman et al. RECE!	/FD 12/07/99	
		5,999,319		Castracane	12-07-1999	
-		6,061,166		Furlani et al. AUG 2 1	2002 05-09-2000	
		6,144,481		Kowarz et al	11-07-2000	
-		6,169,624	B1	Godil et al. Technology Ce	nter 2600 1-02-2001	
		6,172,796	B1	Kowarz et al.	01-09-2001	
	1 1	6,175,443	B1	Aksyuk et al.	01-16-2001	
-		6,181,458		Brazas, Jr. et al.	01/30/01	
		6,188,519	B1	Johnson	02-13-2001	
		6,215,579	B1	Bloom et al.	04-10-2001	

#### FOREIGN PATENT DOCUMENTS

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		Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)

OTHER ART -- NON PATENT LITERATURE DOCUMENTS

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		NONLINEAR FLEXURES FOR STABEL DEFLECTION OF AN ELECTROSTATICALLY ACTUATED MICROMIRROR, BURNS et al., Air Force Institute of Technology, Dept. of Ele and Comp Eng., Wright-Patterson AFB, Ohio, SPIE Vol. 3226, 1997, pp 125-136					
		SYNTHETIC SPECRA; A TOOL FOR CORRELATION SPECTROSCOPY, SINCLAIR et al., Applied Optics, Vol. 36, No. 15 05/20/97, pp 3342-3348					

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AUG 19	MOL E							
PORM PTO	0-1449 and B (M	odifie	i)	APPLICATION NO.: 10/09	90,381	ATTY. DOCKET NO.: P00743/70003		
				FILING DATE: Marc	FILING DATE: March 4, 2002			
STATEMENT BY APPLICANT				APPLICANT: Step	APPLICANT: Stephen D. SENTURIA			
Sheet	6	of	9	GROUP ART UNIT:		EXAMINER:		

Examiner's Initials #	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue of Cited Document
	No.	Number	Kind Code	Document	MM-DD-YY
		6,233,087	B1	Hawkins et al.	05-15-2001
		6,238,581	B1	Hawkins et al.	05-29-2001
		6,243,194	B1	Brazas, Jr. et al.	06-05-2001
		6,252,697		Hawkins et al. RECE	VED 06/26/01
	6,268,952		B1	Godil et al.	07-31-2001
	Ì	6,282,012	B1	Kowarz et al. AUG 2	<b>2002</b> 08-28-2001

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Technology Center 2600

Evenines's	Cite	Foreign Patent Document  Office/ Country  Number  Name of Patentee or Applicant of Cited Document (not necessary)  Date of Publication of Cited Document MM-DD-YY  Translation (Y/N)				
DAMINIOI 5	No.		Number	Document	Document	_

OTHER ART -- NON PATENT LITERATURE DOCUMENTS

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		SYNTHETIC INFRARED SPECRA, SINCLAIR et al., Optical Society of America, Optical Letters, vol. 22, No. 13 07/01/97, pp 1036-1038		
		ELECTROSTATIC EFFECTS IN MICROMACHINED ACTUATORS FOR ADAPTIVE OPTICS, HORENSTEIN, et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, J. of Electrostatics, pp 69-81 (1997)		
		ANALYSIS OF GRATING LIGHT VALVES WITH PARTIAL SURFACE ELECTRODES, FURLANI et al., J. Appl. Phys. 83 (2), 01/15/98, American Institute of Physics, pp 629-634		
		POSITIONING, CONTROL, AND DYNAMICS OF ELECTROSTATIC ACTUATORS FOR USE IN OPTICAL AND RF SYSTEMS, E.S. HUNG, 08/21/98 thesis Massachusetts Institute of Technology, 107 pages		
		OPTICAL PHASE MODULATION USING A REFRACTIVE LENSLET ARRAY AND MICROELECTROMECHANICAL DEFORMABLE MIRROR, COWAN et al., AFRL/MLP, Optical Engineering, Vol. 37 No. 12, 12/123/98, pp 3237-3247		
•		LEVERAGED BENDING FOR FULL-GAP POSITIONING WITH ELECTROSTATIC ACTUATION, E.S. HUNG et al., MIT, Solid-State Sensor and Actuator Workshop Hilton Head Island, SC 06/08/98-06/11/98 pp 83-86		

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[NOTE - Must provide a copy of any patent, publication, other information listed, even if it was previously submitted to, or cited by, the U.S. Patent Office in an earlier application, unless the earlier application is identified by the IDS and is relied upon for an earlier filing date under 35 U.S.C. §120, and the copy was provided in the earlier application.]

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AUG 1	1 P	, scro			•			•	
PORM	PTO	100	A and B (M	lodifie	d)		APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003
	INF	ORM	IATION	DIS	CLOS		FILING DATE:	March 4, 200	)2
	STA	ATEN	IENT B	Y A	PPLIC	ANT	APPLICANT:	Stephen D.	SENTURIA
Sheet			7	of		9	GROUP ART UNIT:		EXAMINER:

Examiner's Initials #	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue
	No.	Number	Kind Code	Document	of Cited Document MM-DD-YY
		6,282,213	B1	Gutin et al. RECEIV	O8-28-2001
		6,284,560	B1	Jech, Jr. et al.	09-04-2001
		6,288,824	B1	Kastalsky AUG 2 1	002 09-11-2001
		6,329,738	B1	Hung et al.	12-11-2001
				lechnology Cen	ter 2600

#### FOREIGN PATENT DOCUMENTS

Everimen's	Cite	Foreign Patent Document			Name of Patentee or Applicant of Cited	Date of Publication of	Translation
Examiner's Initials #	Cite No.	Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	Translation (Y/N)

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Initials#	No	item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue	(Y/N)
		number(s), publisher, city and/or country where published.	
		MEMS DEFORMABLE MIRRORS FOR ADAPTIVE OPTICS, BIFANO, et al., Dept. of Aerospace and Mech.	
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